

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	13	(simulation) and (threshold same (resist adj model)) and (table)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:48
L2	115	(simulation) and (threshold same ((look-up adj table) or LUT))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:52
L3	3	(resist adj model) and (threshold same ((look-up adj table) or LUT))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 14:02
L4	3	(resist adj model) and (threshold and ((look-up adj table) or LUT))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 14:02
S1	1092	716/19	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:12
S2	783	716/21	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:12
S3	1	(716/19).ccls. and (wafer adj simulation) and (threshold adj data)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14
S4	0	(716/21).ccls. and (wafer adj simulation) and (threshold adj data)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14
S5	0	(716/21).ccls. and (wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14
S6	2	(716/19).ccls. and (wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14

S7	2	("716"/\$).ccls. and (wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:15
S8	3	(wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:16
S9	39	(wafer and simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:38
S10	3	(wafer and simulation) and (threshold same (resist adj model)) and ((look-up adj table) or LUT)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:07

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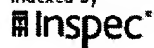
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Erhardt, J.; Phan, K.; Backe, E.; Tran, Q.; Fletcher, B.; Hopper, C.B.; Peterson  
Advanced Semiconductor Manufacturing Conference and Workshop, 2000 IEE  
12-14 Sept. 2000 Page(s):96 - 102  
Digital Object Identifier 10.1109/ASMC.2000.902566  
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- ☐ 2. **Correlation between printability and visibility of defects in EUV mask blar**  
Ito, M.; Tezuka, Y.; Terasawa, T.; Tomie, T.;  
Microprocesses and Nanotechnology Conference, 2003. Digest of Papers. 200  
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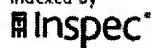
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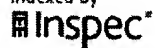
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